

**NAME:** Prof. Dr. Egbert Oesterschulze

Date of birth 04.09.1962

Family status married, 2 children



**ADDRESS**

University of Kaiserslautern  
Department of Physics  
Erwin-Schrödinger-Strasse  
67663 Kaiserslautern, Germany  
[www.physik.uni-kl.de/oesterschulze](http://www.physik.uni-kl.de/oesterschulze)

Phone: +49 (0)631 205 2680

Fax: +49 (0)631 205 2394

E-mail: [oester@physik.uni-kl.de](mailto:oester@physik.uni-kl.de)

**PROFESSIONAL CARRER:**

|             |  |
|-------------|--|
| 1983 – 1989 | Course in Experimental Physics, Westfälische Wilhelms Universität Münster, Germany   |
| 1989 – 1990 | Industrial Cooperation on Laser Lithography, Märzhäuser GmbH (Wetzlar), Germany  |
| 1990 – 1994 | PhD, University of Kassel, Germany   |
| June 1994   | PhD defense  |
| 1995        | PostDoc at IBM Almaden Research Center (Prof. Dr. H. Coufal), USA  |
| 1995        | Research Assitant (C1) University of Kassel  |
| 2000        | Habilitation at University of Kassel   |
| 2002        | Assistant Professor (C2) at University of Kassel   |
| 2004        | Chair for Physics and Technology of Nanostructures, (C3) University of Kaiserslautern, Germany   |
| Since 2005  | Chair of the regional union Hessen-Mittelrhein-Saar as part of the German Physical Society (Deutsche Physikalische Gesellschaft (DPG)) |
| 2005        | Chair for Physics and Technology of Nanostructures, (W2) University of Kaiserslautern  |

**RESEARCH:**

- Development of microsystems on base of microelectromechanical system (MEMS) technologies
- Development of:
  - apertures / antenna probes for scanning near-field optical microscopy
  - active emitting near-field probes
  - ultrafast sampling probes with integrated Austin switch
  - superhard diamond probes for engraving ultrasmall electronic devices
  - Schottky diode based probes for thermal imaging etc.
- Development of high frequency mechanical microresonators for fluid operation with high Q values

## THE TEN MOST IMPORTANT PUBLICATIONS:

### EC-Bauelemente

1. T. Deutschmann, C. Kortz, L. Walder, E. Oesterschulze, High Contrast Electrochromic Iris, *Optics Express*, 23(24), 31544, 2015.
2. T. Deutschmann, E. Oesterschulze, Integrated electrochromic iris device for low power and space-limited applications, *J. Opt.*, 16, 075301, 2014.
3. D. Pätz, T. Deutschmann, E. Oesterschulze, St. Sinzinger, Depth of focus analysis of optical systems using tunable aperture stops with a moderate level of absorption, *Appl. Opt.*, 53 (28) 6508, 2014.

### Mikroresonatoren

1. S. Klingel, E. Oesterschulze, Investigating the wetting behavior of a surface with periodic reentrant structures using integrated microresonators, *Appl. Phys. Lett.*, 111, 061604, 2017.
2. C. Kortz, E. Oesterschulze, Spatial and directional control of self-assembled wrinkle patterns by UV light absorption, *Appl. Phys. Lett.*, 111, 231904, 2017.
3. J. Menges, P. Kleinschmidt, H.-J. Bart, E. Oesterschulze, A precision structured smart hydrogel for sensing applications, *Appl. Phys. Lett.*, 122, 134501, 2017.
4. P. Peiker, E. Oesterschulze, Virtual mass effect in dynamic micromechanical mass sensing in liquids, *Appl. Phys. Lett.*, 108, 241904, 2016.
5. P. Peiker, S. Klingel, J. Menges, H.-J. Bart, E. Oesterschulze, A partially wettable micromechanical resonator for chemical- and biosensing in solution, *Procedia Engineering*, 168, 606-609, 2016.
6. P. Peiker, E. Oesterschulze, Geometrically tuned wettability of dynamic micromechanical sensors for an improved in-liquid operation, *Appl. Phys. Lett.* 107, 101903, 2016.
7. P. Peiker, E. Oesterschulze, Geometrically tuned wettability of dynamic micromechanical sensors for an improved in-liquid operation, *Appl. Phys. Lett.*, 107, 101903, 2015.